

IN THE CLAIMS

This listing of claims will replace all prior versions and listings of claims in the application:

Claims 1-5 (Cancelled)

Claim 6. (Currently Amended): A probe array used in a manufacturing process of a probe card, comprising:

a second film-shaped supporting [[12]] body; and

a plurality of probes, ~~each being recited in claim 1~~, adhered onto one surface of the second film-shaped supporting body, each probe including: a beam and a contactor having a substantially trapezoidal shape,

wherein the beam has a leading end, an intermediate portion and base end, the leading end being a portion for making a contact with the test subject via the contactor, the base end being a portion for fixing the probe; and wherein the contactor is installed to the leading end of the beam.

Claim 7. (Original): The probe array of claim 6, wherein at least portions of said one surface of the second film-shaped supporting body where the probes are attached have an adhesive property, and an adhesive strength thereof can be varied by heat or ultraviolet light.

Claim 8. (Currently Amended): The probe array of claim 6, wherein a surface of each beam of the plurality of probes [[4]], with a corresponding contactor being installed at the

surface, is adhered to the surface of the second film-shaped supporting body having an adhesive property.

Claim 9. (Original): The probe array of claim 6, wherein the plurality of probes are arranged in various directions on a film.

Claim 10. (Currently Amended): A method for manufacturing the probe array recited in claim 6, comprising the steps of:

[a] forming the plurality of probes on the silicon substrate ~~10 by the manufacturing method of claim 4~~ by using a lithography technology, including the steps of:

(a1) forming on a silicon substrate a plurality of recessed portions, each having a substantially trapezoidal shape, by using an anisotropic etching technique, wherein an area of a top surface of the trapezoidal shape is controlled by adjusting an etching time; and

(a2) forming a plurality of probes by using a film forming technique on the silicon substrate, wherein a contactor of each probe is formed inside each recessed portion having the trapezoidal shape and at the same time the beam is formed on the silicon substrate together with the contactor as a single body,

wherein the probe includes a beam and a contactor having a substantially trapezoidal shape, the beam having a leading end, an intermediate portion and base end, the leading end being a portion for contacting with the test subject via the contactor, the base end being a portion for fixing the probe; and the contactor is installed to the leading end of the beam;

[b] transferring the plurality of probes formed on the silicon substrate $[[10]]$ onto one surface of a first film-shaped supporting body $[[11]]$ simultaneously;

[c] deteriorating an adhesive property of said one surface of the first film-shaped supporting body; and

[d] transferring the plurality of probes onto said one surface of the second film-shaped supporting body by adhering the latter onto said one surface of the first film-shaped supporting body.

Claim 11. (Currently Amended): The method of claim 10, wherein said one surface of the first film-shaped supporting body $[[11]]$ has the adhesive property and an adhesive strength thereof can be varied by heat or ultraviolet light.

Claim 12. (Currently Amended): The method of claim 10, wherein the step [a] includes the steps of:

[a'] forming a peeling layer on the silicon substrate prior to forming the plurality of probes on the silicon substrate by the method of step [a]; and

[b'] eliminating parts of the peeling layer prior to transferring the plurality of probes formed on the silicon substrate $[[10]]$ onto said one surface of the first film-shaped supporting body simultaneously.

Claim 13. (Currently Amended): A method for attaching a base end of a probe to a supporting column [[3]] placed on a card shaped substrate [[2]], comprising the steps of:

providing a probe array as set forth in claim 6;

installing the base end of ~~the probe~~ a probe of the plurality of probes having the trapezoidal contactor ~~of claim 1~~ and accommodated in the probe array ~~of claim 6~~ on an attaching surface [[3 a]] of the supporting column [[2]] on the card shaped substrate [[2]]; and

fixing the base end of the probe to the supporting column.

Claim 14. (Original): The method of claim 13, wherein the step of fixing the base end of the probe to the supporting column is performed by pressing a leading end of an ultrasonic bonder against an upper side of the base end of the probe,

wherein the leading end of the ultrasonic bonder has a crossed protrusion, a cross section of the protrusion being of a substantially semicircle, and the beam of the probe is bent toward the contactor by fixing the base end of the probe to the supporting column by using the ultrasonic bonder.

Claims 15-25. (Cancelled)